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WHAT IS CLAIMED IS:

relative to each other.

| 1 | 1. A method for maintaining a consistent pressure between two chambers | | |
|----|---|--|--|
| 2 | in a processing facility, wherein the two chambers have a slit valve there | | |
| 3 | between, the method comprising the steps of: | | |
| 4 | determining when the slit valve is open; | | |
| 5 | measuring a pressure of the first chamber while the slit valve is open; | | |
| 6 | measuring a pressure of the second chamber while the slit valve is open | | |
| 7 | calibrating first and second pressure sensors, associated with the first | | |
| 8 | and second chambers, respectively, relative to each other while the slit valve is | | |
| 9 | open; and | | |
| 10 | closing the slit valve when the pressure sensors have been calibrated | | |

- 2. The method of claim 1 wherein the slit valve is a vacuum-sealed door.
- 3. The method of claim 1 wherein the calibrating is performed by changing a reading value of the first pressure sensor to be in accordance with the second pressure sensor.
- 4. The method of claim 3 wherein the second chamber is a transfer chamber connecting the first chamber to a third chamber.
- The method of claim 3 further comprising:

 monitoring the change of the reading value of the first sensor; and
 determining if the change indicates a faulty system.

| 6. | A method for maintaining a consistent pressure in a processing facility |
|-------|---|
| havin | g a transfer chamber used to transfer materials to and from a process |
| cham | ber, wherein the two chambers have a valve there between, the method |
| comp | rising the steps of: |
| | dot |

determining when the valve is open;

measuring a pressure of the transfer chamber while the valve is open;

measuring a pressure of the processing chamber while the valve is open;

calibrating a pressure sensor on the processing chamber relative to a

pressure sensor on the transfer chamber while the valve is open; and

closing the valve when the pressure sensors on the processing chamber

and transfer chamber are relatively calibrated.

7. The method of claim 6 wherein the transfer chamber is also used to transfer materials to and from a loading chamber, the transfer chamber and loading chamber having a second valve there between, the method further comprising:

determining when the second valve is open;

measuring a pressure of the transfer chamber while the second valve is open;

measuring a pressure of the loading chamber while the second valve is open;

calibrating a pressure sensor on the loading chamber relative to the pressure sensor on the transfer chamber while the second valve is open; and closing the second valve when the pressure sensors on the loading chamber and transfer chamber are relatively calibrated.

| 1 | 8. An automated system for controlling processing of a product in a | | |
|----|---|--|--|
| 2 | processing facility, said system compromising: | | |
| 3 | first, second, and third chambers; | | |
| 4 | first, second, and third pressure sensors associated with the first, | | |
| 5 | second, and third chambers, respectively, for measuring a pressure inside each | | |
| 6 | chamber; | | |
| 7 | first, second, and third exhaust lines connected to the first, second, and | | |
| 8 | third chamber, respectively; | | |
| 9 | first, second, and third pressure restriction control valves connected to | | |
| 10 | the first, second, and third exhaust lines, respectively; | | |
| 11 | a first material transfer valve connecting the first chamber to the second | | |
| 12 | chamber; | | |
| 13 | a second material transfer valve connecting the second chamber to the | | |
| 14 | third chamber | | |
| 15 | a control module connected to the first and second material transfer | | |
| 16 | valves, the first, second and third pressure sensors, the first, second and third | | |
| 17 | variable restriction control valves, and the first, second and third chambers, | | |
| 18 | the control module including processing capabilities for performing the steps | | |
| 19 | of: | | |
| 20 | measuring the pressure in the first and second chamber while the | | |
| 21 | first material transfer valve is closed; | | |
| 22 | adjusting the first and second variable restriction control valves | | |
| 23 | until the first and second pressure sensors have similar readings while | | |
| 24 | the first material transfer valve is closed; and | | |
| 25 | calibrating the first pressure sensor to generate a reading similar | | |
| 26 | to that of the second pressure sensor when the first material transfer | | |
| 27 | valve is open. | | |

| 1 | 9. | The system described in claim 8 wherein the first and second material | | | |
|-----|-------|---|--|--|--|
| 2 | trans | sfer valves are vacuum-sealed doors. | | | |
| 1 | 10. | The system described in claim 8 wherein the transfer chamber includes | | | |
| 2 | a rob | oot for handling of the materials being processed. | | | |
| 1 | 11. | The system described in claim 8 wherein the control module also | | | |
| 2 | inclu | includes processing capabilities for: | | | |
| 3 | | detecting a fault in the system by monitoring the adjustment of | | | |
| 4 | | the first pressure sensor over a period of adjustments. | | | |
| 1 . | 12. | The system described in claim 8 wherein the control module also | | | |
| 2 | inclu | includes processing capabilities for: | | | |
| 3 | | measuring the pressure in the second and third chambers while | | | |
| 4 | | the second material transfer valve is closed; | | | |
| 5 | | adjusting the second and third variable restriction control valves | | | |
| 6 | | until the second and third pressure sensors have similar readings while | | | |
| 7 | | the second material transfer valve is closed; and | | | |
| 8 | | calibrating the third pressure sensor attached to the third | | | |
| 9 . | | chamber to generate a reading similar to that of the second pressure | | | |
| 10 | | sensor when the second material transfer valve is open. | | | |
| 1 | 13. | The system described in claim 12 wherein the control module also | | | |
| 2 | inclu | des processing capabilities for: | | | |
| 3 | | detecting a fault in the system by monitoring the adjustment of | | | |
| 4 | • | the first, second, and third pressure sensors over a period of | | | |
| 5 | | adjustments. | | | |

| 1 | 14. | The system described in claim 13 wherein the control module also |
|---|-------|--|
| 2 | inclu | des processing capabilities for: |
| 3 | | determining that the fault is associated with the third chamber if |
| 4 | | only the third sensor requires significant adjustment over the period of |
| 5 | | adjustments. |
| | | |
| 1 | 15. | The system described in claim 13 wherein the control module also |
| 2 | inclu | les processing capabilities for: |
| 3 | | determining that the fault is associated with the second chamber |
| 4 | | if both the first and third sensors require significant adjustment over |
| 5 | | the period of adjustments. |
| | | |